

Ref. e-Tender Notice No. NITJ/PUR/107/20/ e-tender no. 104/2021

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Assistant Registrar Dr. B. R Ambedkar NIT Jalandhar Email: <u>arpurchase@nitj.ac.in</u>



THIS DOCUMENT IS FOR REFERENCE ONLY. ONLY E-TENDERS WILL BE ACCEPTED

e-Tender Notice No. NITJ/PUR/107/20/ e-tender no. 104/2021

National Institute of Technology, Jalandhar invites e-tender for Purchase of **High Resolution transmission electron Microscope (HRTEM) With Accessories** required for **Institute Instrumentation Center Department** as per detail available at <u>Annexure-I</u> along with Tender Fee & EMD as per details given below:

I	Downloading & Submission of Online e-tender/bids	Start Date: 14.01.2022 at 03:00 PM
II	Last date of submission of online bids	End Date: 04.02.2022 upto 03:00 PM
111	Physical submission of Tender Fee and EMD	End Date: 07.02.2022 upto 03:00 PM
IV	Opening of Technical e-Bid (online)	07.02.2022 at 03:00 PM

Detailed Terms and Conditions are available in e-tender document. The bid document can be downloaded from the <u>CPP Portal</u>.

Complete tender document is available for reference purposes on Institute website <u>www.nitj.ac.in</u> and <u>CPP Portal.</u> Only e-tenders will be accepted.

NOTE: This is a domestic Tender according to the DPIIT Order dated 16.09.2020 and subsequent amendments to the order for Public Procurement Preference & PROVISION FOR LOCAL SUPPLIERS TOWARDS PREFERENCE TO MAKE IN INDIA. The bidder required to declare on the letter head the percentage of Local content for the quoted instrument/Item and submit with the Technical Bid as per Annexure-G. Bidder should also give details of the location(s) at which the local value addition is made in the Annexure.

Registrar



Annexure-I

Ref. No. e-Tender Notice No. NITJ/PUR/107/20/ e-tender no. 104/2021

Detail of Equipment, Tender Fee & EMD are as under:

Sr. no.	Item/Equipment	Qty.	Tender Fee	EMD
1	High Resolution transmission electron Microscope (HRTEM) With Accessories	01 no.	Rs. 500/-	Rs. 8,20,000/-

Note: The quantity of required equipment/item may vary as per requirement.

*Exemption of Tender fee & EMD will only be given to MSME/NSIC registered bidders.



Important Note

- 1. All corrigenda, addenda, amendments and clarifications regarding this tender document will be uploaded on the website <u>www.nitj.ac.in</u> and CPP Portal and not in the newspaper; Bidders shall keep themselves updated with all such developments.
- 2. In case, the last date of receipt/opening of bids falls on holiday, the bids shall be receipt/opened on the next working day at same time.
- 3. In case, the last date of submission of EMD & Tender fee falls on holiday, the EMD & Tender fee shall be submitted on the next working day at same time.
- 4. Tenderer who have downloaded the tender document form from the institute website, shall submit a declaration along with tender document that I/We have downloaded the Tender Form from the institute website <u>www.nitj.ac.in</u> and I/we have not tempered /modified the tender form in any manner. In case, if the same is found to be tempered/modified in any manner, I/we understand that my/our tender will be summarily rejected and I/we are liable to be banned from doing business with institute.
- 5. Tender fee of Rs.500/- (Non- refundable) in the form of DD in favour of <u>Director, D</u> <u>R B R Ambedkar NIT, Jalandhar.</u>
- 6. EMD (refundable) in the form of DD in favour of <u>Security- A/c, DR B R Ambedkar</u> <u>NIT, Jalandhar</u>.
- 7. <u>Both EMD and Tender fee are be submitted as per dates mentioned in schedule,</u> <u>failing which e-bids will not considered.</u>
- All the bidders are required to submit the Tender Fee and EMD as per requirement of tender document failing which bids received straightway rejected and bid will be treated invalid.
- Note: If the bidder inadvertently or otherwise upload the quoted rates in the technical bid, the bid will be straightway rejected and treated invalid.
- If the bidder is exempted for payment of Tender Fee and EMD as NSIC/MSME registered bidders, then bidder is required to submit NSIC/MSME exemption certificate for same. The Certificate must be valid as on last date of submission of bid.

Tenderer must submit a scanned copy (duly signed and stamped) regarding terms & conditions as per our tender documents along-with make/model, specifications, bill of quantity as per required equipment in the technical bid for examine the bid as per our institute tender documents. It is noted that no rate should be depicted in the letter head.



Instructions to Tenderer

- 1. No tender will be accepted in physical form. The bidders shall have to submit their bids online in Electronic Format under Digital Signatures. For participation in the e-tendering process, the bidders need to register themselves on CPP Portal.
- 2. Bids are to be submitted online and opened online as per time given failing which no tender will be considered.
- 3. Bids will be opened online as per time given schedule.
- 4. Before submission of online bids, bidders must ensure that scanned copies of all the necessary/relevant documents have been uploaded with the bid which should be duly signed and stamped. The duly signed and stamped copies of Terms & Conditions of the tender, reply of the Questionnaire of Plant & Machinery and other documents of the Tender & Annexures must be uploaded, failing which their bids may be rejected.
- 5. NIT JALANDHAR, will not be responsible for any delay in online submission of bids due to any reason whatsoever.
- 6. Bidders should also upload the scanned copies of Tender fees/EMD/Exemption Certificate as specified in the tender documents along with online technical documents. EMD in the form of a Demand Draft in favour of the <u>Security – A/c</u>, <u>Dr B R Ambedkar NIT, payable at Jalandhar</u> (refundable separate) and Tender Fee in the form of a Demand Draft in favour of the <u>Director, Dr B R Ambedkar</u> <u>NIT, payable at Jalandhar</u> (Non- refundable separate) should also be submitted in physical form to the following address as per scheduled time given for physical submission of EMD and Tender fee. The Envelope should be superscribed as EMD and Tender Fee for Tender for Supply of High Resolution transmission electron Microscope (HRTEM) With Accessories required for Institute Instrumentation Center Department of the Institute and sent to following address:-

Kind Attention- Assistant Registrar (Purchase Section) Director, Dr B R Ambedkar National Institute of Technology, G T Road Amritsar By Pass, Jalandhar-144011, Punjab (India).

- 7. The details of EMD specified in the tender document should be same as submitted online (scanned copies). Otherwise tender will be rejected summarily.
- 8. The conditional bids shall not be considered and will be out rightly rejected.

Read and Accepted



- 9. The Financial Bid through e-tendering process shall be opened of only those bidders, who will qualify in the technical bid and approved by the Purchase Committee/Technical Experts. The date, time & place of opening of the financial bid(s) will be intimated in due course of time.
- 10. At any time prior to the deadline for submission of bid, the institute may, for any reason, whether at its own initiative or in response to a clarification requested by a prospective tenderer(s), modify the tender document by issuance of an amendment.
- 11. The amendment will be uploaded on Institute website and CPP Portal only. In order to provide reasonable time to prospective tenderer(s), for preparing their bid as per amendment, the institute may, at its discretion extend the deadline for the submission of tender.
- 12. The supplier must upload the original manuals / catalogue and Make/Model of the Equipment /Item. Otherwise bid is liable to be rejected.
- 13. The Institute is not liable to pay any interest on EMD. Earnest money deposit shall be forfeited, if the tenderer, withdraws its bid during the period of tender validity. The Earnest money deposit of the tenderer, whose tender has been accepted, will be returned on the submission of <u>performance security @ 3% of the total value of the offer. The performance security will be kept till the warranty period + 02 months more of the Equipment /Item. The warranty period will start from the date of satisfactory installation of the Equipment /Item duly given by the <u>concerned department</u>. Earnest money deposit of the successful tenderer shall be forfeited, if it refuses or neglects to execute the contract or fails to furnish the required performance security within the time frame as specified by the institute. The EMD(s) of other Bidder(s) whose offer are found according to required specifications/ lowest will be released after finalization of Technical Bids/ Lowest Bid/Purchase.</u>
- 14. The Format of Performance Bank Guarantee bond or Performance Bank Guarantee issued by the bank as per the format given in <u>Annexure "B" & "C"</u>.
- 15. Delivery time is the essence of the contract and must be met with.
- 16. Nearest specifications/better specifications can be considered. In case of deviation, complete justification should be furnished with proper documents.
- 17. The Director may accept a tender in part or whole of the quantity offered, reject any tender without assigning any reasons and may not accept the lowest bidder. Further in case of any doubt/dispute, the decision of the Director of the Institute shall be final.
- 18. The offer shall be kept valid for minimum 120 days.

Read and Accepted.



- a) Either the agent/ dealer on behalf of the Principal/OEM or Principal/OEM itself can bid but both cannot bid simultaneously for the same item/product in the same tender.
 - b) If an agent/ dealer submits bid on behalf of the Principal/OEM, the same agent /dealer shall not submit a bid on behalf of another Principal/OEM in the same tender for the same item/product.
 - c) Only one agent/dealer of single Principle/OEM can submit the bid. If more than one agent/dealer of same OEM/Principal quote in the tender, then bids of all the bidders of single OEM/Principle are liable to be rejected.
 - d) All offers other than those from the Principal/OEM should be supported by an authority letter from the manufacturer authorizing the dealer /supplier to tender on their behalf as per <u>Annexure-D</u>. In case of manufacturer, a certificate or a copy thereof to the effect that the bidder is a manufacturer of the Equipment /Item must be accompanied with the technical bid.
- 20. The supplier will be responsible till the entire stores contracted for, arrive in good condition at destination.
- 21. The tenderer should not have been debarred and/ or blacklisted by any Central Government/ or any State Government Department(s). This must be <u>supported by</u> an affidavit as per format given in **Annexure-"E"**.
- 22. If any information furnished by the bidder is, at any stage found to be incorrect/false/fabricated, the Institute shall have the absolute right to forfeit the EMD, warranty/performance guarantees or/and security deposits, in addition to cancellation of contract, and in accordance with law, such other actions may be taken like black-listing of the bidder etc.

Read and Accepted.



TENDER EVALUATION

Institute will evaluate all the proposals to determine whether these are complete in all respects as specified in the tender document. Evaluation of the proposals shall be done in two stages as:

(a) <u>Stage – I (Technical Evaluation):</u>

(i) Institute shall evaluate the technical bid(s) to determine the following like the bid qualifies the essential eligibility criteria or not, the tenderer has submitted the EMD & Tender fee or not, any computational errors have been made or not, all the documents have been properly filled or otherwise, all the documents have been submitted/ uploaded with technical bid or not, the specifications, Make/Model, Catalogue of quoted Equipment /Item are as per requirement tender specifications or not, Authorization of Dealer / Distributor/ Exclusive Agent certificate from manufacturer is in order or not, Sales & service policy of equipment / item during warranty period and after warranty period will also be seen, location of their authorized service center will also be seen for evaluation etc.

After evaluation of technical bid(s), a list of the qualifying tenderer (s)/ bidder s) shall be made. Short-listed tenderer(s) will be informed of the date, time and place of opening of financial bid(s) and they may attend or depute their authorized representative/s to attend the schedule of opening of financial bid(s) on the scheduled date and time, if they wish to do so. The representative(s) should have a letter of authority to attend the price bid(s) opening event.

Read and Accepted



PART – II (e-FINANCIAL BID):

- a) Bidders should offer the rates as per the format of BOQ as available on CPP Portal. Detailed bill of material/quantity is also to be provided along with the price breakup of each item as per requirement of the tendered specification of the equipment in the online price bid at <u>CPP Portal</u>.
- Note: The quoted amount as filled in the Annexure(s) of online financial bid and detailed bill of material/quantity provided with price break up of each item in the online financial bid should be tallied and both must be same, otherwise bid will be treated invalid.

Read and Accepted.



ARBITRATION:

In case of any dispute or difference arising out in connection with the tender conditions/job order/Contract, the Institute and the Seller/Service Provider will address the dispute/difference for a mutual resolution and failing which, the matter shall be referred for arbitration to a sole Arbitrator to be appointed by the Institute.

The Arbitration shall be held in accordance with the provisions of the Arbitration and Conciliation Act, 1996 and the venue of arbitration shall be at Jalandhar only. The decision of the Arbitrator shall be final and binding on both the parties.

JURISDICTION:

The courts at Jalandhar alone will have the jurisdiction to trial any matter, dispute or reference between parties arising out of this tender / contract. It is specifically agreed that no court outside and other than Jalandhar Court shall have jurisdiction in the matter.

Read and Accepted.



(TERMS AND CONDITIONS (FOR THE SUPPLY OF GOODS, EQUIPMENT /ITEM)

1. Rate should be quoted F.O.R NIT Jalandhar and In INR only.

2. Where the Equipment / Machinery/ Instrument are composed of several sub units/components, the rate should be quoted for each subunit/component separately. NIT Jalandhar reserves the right to increase or decrease the number of sub units/components and number of Equipment / Machinery/ Instrument according to its requirements.

3. The institute being government educational institute is having Excise and Custom duty exemption in terms of government notification No. 51/96-customs Dt. 23-7-1996 and No. 10/97-central excise Dt. 1-3- 1997 as amended from time to time, therefore taxes be quoted accordingly and this must be depicted in Price Bid clearly.

4. GST or any other chargeable duty where applicable must be specifically mentioned, failing which no tax or duty will be allowed at subsequent stage.

5. All items shall be indicated both in words as well as in figures. If there is difference between amount quoted in words and figures, amount quoted in words shall prevail.

6. Payment:

(a) 100% payment will be made against physical delivery, inspection, installation, training of the Equipment/Machinery/Instrument etc. in the institute, receipt of satisfactory working report of the Equipment / Machinery/Instrument etc. and receipt of Performance Bank Guarantee @ 3%.

7. Warranty: Rates should be quoted with comprehensive warranty. Besides this, policy regarding after sale service on the expiry of warranty period of Equipment / Machinery/Instrument etc. may be explained. The bidders should attach duly signed and stamped certificate of warranty as per <u>Annexure-F</u> with the technical bid.

8. Training: In house training (where applicable) after the installation and commissioning of Equipment / Machinery/Instrument etc. shall be provided by the supplier.

9. Delivery: Delivery date will be mentioned in the supply order. The time and date of delivery or dispatch stipulated in a supply order shall be deemed to be the essence of the supply order and if the supplier fails to deliver or dispatch any consignment within the period prescribed for such delivery, the delayed consignment will be accepted subject to penalty as laid down in the supply order, which will be recovered from the pending payments.

Read and Accepted.



1. No recovery of penalty will be made, if the delayed supplies are acceptable by extending the delivery period by the Director with our any LD charges.

2. Director will allow extension on the request of the supplier by recording in writing that in exceptional circumstances the supply was beyond the control of the supplier and there was no loss to the institute.

3. Penalty on account of delay, Director NIT, Jalandhar reserves the right to impose 0.5% (Half) per cent penalty per week on account of delay in supply, if delivery received after expiry of the original delivery period. The total penalty will not exceed 10% of the value of the delayed goods.

10. Installation: Supplier has to install the Equipment / Machinery/ Instrument within two to three weeks from the receipt of the Equipment / Machinery/Instrument etc. in NIT Jalandhar.

11. Spares and Accessories, wherever required should be quoted separately and clearly, even if these are not asked for.

12. Site Preparation: The supplier shall inform NIT Jalandhar about the site preparation, if any, needed for the installation, immediately after receipt of the supply order. Supplier must provide complete details regarding space and all infrastructural requirements needed for the Equipment / Machinery/Instrument etc which NIT Jalandhar should arrange before the arrival of Equipment / Machinery/Instrument etc to ensure its early installation and smooth operation thereafter. The supplier may offer his advice and render assistance to NIT Jalandhar in the preparation of the site and other pre installation requirements.

13. The total scope of work includes the supply, installation, satisfactory commissioning and testing of the Equipment / Machinery/Instrument etc by the supplier, training at NIT Jalandhar, method development and validation for parameters as mentioned in specifications at <u>Annexure-A</u>. The supplier will complete installation & Commissioning of Machine within two to three weeks from the date of receipt of Equipment / Machinery/Instrument etc. of NITJ.

14. Details about the service center for the quoted Equipment / Machinery/Instrument etc. in India may be mentioned.

Read and Accepted.



Acceptance

We_____ read and accept the instructions to the tenderer, terms & conditions and all other documents as mentioned in the tender and shall comply with them strictly.

Name of Bidder _____

Signature

Address			

Seal of firm:

Date:

Dr B R AMBEDKAR NATIONAL INSTITUTE OF TECHNOLOGY



G T Road By Pass, Jalandhar-144011, Punjab (India) EPABX-0181-2690301 & 453 website: <u>www.niti.ac.in</u> email: <u>registrar@niti.ac.in</u>

Questionnaires A & B

QUESTIONNAIRE FOR PLANT & MACHINARY

Note: Please submit the reply in detail and also enclose the necessary documents with proof where required as per Questionnaire. These documents must be submitted in the technical bid document.

Please state that you have submitted your quotations as per procedure mentioned below:-

- Bids consisting of technical details bringing out clearly in a separate sheet ,the deviation in the specifications if any from that of tender enquiry specifications along with commercial terms and tender form.
- 1. Please attach list dully signed by you, for such spare parts and tools which are absolutely essential for proper maintenance and operation of machine for a period of two years giving full particulars of spare and tool with a price of each spare parts and tools separately.
- 2. Please confirm that you have adequate servicing and spare parts facilities in India in respect of Equipment /Item tendered by you or that you should arrange to provide such facilities simultaneously.
- 3. Please indicate that you guaranteed that before going out of production of spare parts, you will give adequate advance notice to the purchaser so that the institute may order his requirements of spares in one lot, if he so desire.
- 4. Please indicate that you guaranteed that if you go out of production of spare parts, then you will make available prints, drawings of the spare parts and specifications of the material at no cost if and when required in connection with Equipment /Item to enable the purchaser to fabricate or procure spare parts from other sources.
- 5. Please confirm that you undertake to enter into a rate contact with the
- purchaser to supply spare parts on an agreed basis for an agreed period.
- 6. Status:
 - a) Indicate whether you are ISU or SSI
 - b) Are you registered with Government e-Marketing (GeM) for the item quoted? If so indicate whether there is any monetary limit or registration.
 - c) If you are a small scale unit registered with NSIC under single point registration scheme whether there is monetary limit.
- 7. a) If you are registered either with NSIC or with Government e-Marketing (GeM), please State whether you are registered with Directorate of industries of the state government concerned.

b) If so, confirm whether you have attached a copy of the certificate, issued by Director of industries.

- 8. Please indicate:-Name & Full Address of your Banker
- 9. Please indicate whether you agree to submit advance samples if called upon to do so within the specified period of 21 days.



10. Business name and constitution of firm:-

i)The Indian company Act.1956
ii)Indian partnership Act.1932
iii)Any act, if not, who are the owner/partners (please give full name and address)

- 11. Whether the tendering firm is / are:
 - i) Manufacturers authorized agents
 - ii) Holders stock of the stores tendered for
 - iii) NBI manufacturer's agents please enclose with tender the copy of manufacturer's authorization.
- 12. Please state whether the inspection clause is acceptable to you
- 13. Here state specifically:
 - i) Whether the price quoted by you is to the best of your knowledge and belief is not more than the price usually charged by you on stores of the same natures, class of description to any private purchase either foreign or as well as government purchaser. If not state the reason thereof if any also indicates the margin of Difference.
 - ii) In respect of indigenous items for which there is a controlled price fixed by law, the price quoted shall not be higher than that the controlled price and rates available on DGS&D/ Government e-Marketing (GeM) contract. The reason thereof should be stated.
- 14. State whether business dealing with you has been banned by Ministry /Department of supply or any other Govt. Department.
- 15. Please confirm that you have read all the instruction carefully and have complied with accordingly.

(Signature of Tenderer)

1. Full Name & Address of the person signing

Whether signing as proprietor /partners



PERFORMA FOR PERFORMANCE STATEMENT

(For the Period of last 3 years)

e-Tende	e-Tender Notice No. NITJ/PUR/107/20/ e-tender no. 104/2021				
Sr. No.	Order (full placed address of purchaser)	Order No. & dated	Description And Qty. of Stores Ordered	Value of Order	Has the Equipment/Item been satisfactory commissioned



Dr B R AMBEDKAR NATIONAL INSTITUTE OF TECHNOLOGY

G T Road By Pass, Jalandhar-144011, Punjab (India) EPABX-0181-2690301 & 453 website: <u>www.nitj.ac.in</u> email: <u>registrar@nitj.ac.in</u>

Annexure "A"

TENDER SPECIFICATIONS for HRTEM- High Resolution Transmission Electron Microscope (A) Detailed Specifications:

attice resolution ≤0.14 nm (or better) with a high resolution pol piece compatible with EDS and tomography. The model quoted shall be able to handle metallic (magnetic as we as non magnetic) samples. 2. Magnification 30 X to 1500000 X or more 3. Acceleration Voltage Upto 200 kV- user changeable from 80kV- 200 kV (In steps of continuous to be specified) 4. Electron Emitter • Electron Beam Source with Standard Lab6 Emitter# (or other equivalent emitter having compatibility with the acc. Voltage) 5. Chamber Gonizonter stage, fully computer-controlled, queentics wide-entry, high stability Goniometer maximum tilt should be t/-70 degrees or higher Minimum specimen tilt angle with a standard single tilt holder should be (α/β) ±30 ⁷ t/±30 ^o X movement range - 1 mm in total or more X movement range - 10 mm in total or more Specimen gid size 3 mm 6. Specimen holders • Single ült holder 7. Specimen tilt ± 30 ^o or more with standard holder ± 10 ^o or more with standard holder ± 10 ^o or more high tilt holder / retainer 8. Vacuum System Fully Dry-Vacuum system for the HRTEM (Column and Gun Section) with all required backing pumps, high vacuum pumps and Ultra-High Vacuum Pumps, suitable Pressure Gauges. Compressors and Suitable Air & Water Chillers et required for HRTEM operation. should be <2x 10 ^o Pa 9. Lens System System consisting of condenser lens, objective lens, diffraction, intermediate and projection lenses 10. Permissible Drifts	(A) D	etailed Specifications:	
piece compatible with EDS and tomography. The model quoted shall be able to handle metallic (magnetic as we as non magnetic) samples. 2. Magnification 30 X to 1500000 X or more 3. Acceleration Voltage Upto 200 kV- user changeable from 80kV- 200 kV (In steps or continuous to be specified) 4. Electron Emitter • Electron Beam Source with Standard Lab6 Emitter# (or othe equivalent emitter having compatibility with the acc. Voltage) 5. Chamber Goniometer stage, fully computer-controlled, eucentric side-entry, high stability Goniometer maximum tilt should be 1/-70 degrees or higher Minimum specimen tilt angle with a standard single tilt holder should be (a/β) ±30° /-/30° 6. Specimen holders • Single tilt holder 7. Specimen holders • Single tilt holder 8. Vacuum System Fully Dry-Vacuum system for the HRTEM (Column and Gun Section) with all required backing pumps, high vacuum pumps and Ultra-High Vacuum Pumps, suitable Pressure Gauges, Compressors and Suitable Air & Water Chillers et required for HRTEM operation. 9. Lens System Fully Dry-Vacuum system for the HRTEM (Column and Gun Section) with all required backing pumps, high vacuum pumps and Ultra-High Vacuum Pumps, suitable Pressure Gauges, Compressors and Suitable Air & Water Chillers et required for HRTEM operation. 9. Lens System System consisting of condenser lens, objective lens, diffraction, intermediate and projection lenses 10.<	1.	Resolution	TEM/HRTEM: Point-to-point resolution ≤ 0.24 (or better) nm and
The model quoted shall be able to handle metallic (magnetic as we as non magnetic) samples. 30 Acceleration Voltage Wagnification 10X to 150000 X or more Acceleration Voltage Upto 200 kV- user changeable from S0kV - 200 kV (In steps or continuous to be specified) Electron Emitter • Electron Beam Source with Standard Labé Emitter# (or othe equivalent emitter having compatibility with the acc. Voltage) • Filament should be pre-centered • 2 nos of additional filaments to be supplied as if when required Chamber Goniometer stage, fully computer-controlled, eucentric side-emry, high stability (Goniometer maximum tilt should be +/-70 degrees or higher Minimum specimen tilt angle with a standard single tilt holder should be (a/β) ±30° /±30° Specimen holders • Single tilt holder • Low emission holder for EDS analysis (1 no) * Single tilt holder • Low emission holder for the HRTEM (Column and Gun Section) with all required hocking pumps, high vacuum pumps and Ultra-High Vacuum Pumps, suitable Pressue Gauges, Compressors and Suitable Air & Water Chillers et er equired for HRTEM operation. 8. Vacuum System Fully Dry-Vacuum system for the HRTEM (Column and Gun Section) with all required backing pumps, high vacuum pumps and Ultra-High Vacuum Pumps, suitable Pressue Gauges, Compressors and Suitable Air & Water Chillers et er equired for HRTEM operation. 9. Lens System System consisting of condenser lens, objective lens, diffraction, intermediate and p			lattice resolution ≤ 0.14 nm (or better) with a high resolution pole
as non magnetic) samples. 2. Magnification 30 X to 150000 X or more 3. Acceleration Voltage Upto 200 kV- user changeable from S0kV - 200 kV (In steps or continuous to be specified) 4. Electron Emitter • Electron Ream Source with Standard Lab6 Entiter# (or othe equivalent emitter having compatibility with the acc. Voltage) 5. Chamber • Electron Emitter having compatibility with the acc. Voltage) 5. Chamber Goniometer stage, fully computer-controlled, cucentric side-entry, high stability Goniometer maximum it should be t-/-70 degrees or higher Minimum specimen tilt angle with a standard single tilt holder should be (α/β) ±30° / ±30° / ±30° / ±30° moreent range - 1 mm in total or more Z movement range - 0.10 mm in total or more Specimen gid size 3 mm 6. Specimen holders • Single tilt holder 7. Specimen tilt = 30° or more with standard holder = 00000000000000000000000000000000000			piece compatible with EDS and tomography.
2. Magnification 30 X to 1500000 X or more 3. Acceleration Voltage Upto 200 kV- user changeable from 80kV- 200 kV (in steps or continuous to be specified) 4. Electron Emitter • Electron Beam Source with Standard Lab6 Emitter# (or othe equivalent emitter having compatibility with the acc. Voltage) 5. Chamber Goniometer stage, fully computer-controlled, eucentric side-entry, high stability Goniometer maximum itil should be γ-70 degrees or higher Minimum specimen tilt angle with a standard single tilt holder should be (α/β) ±30° / ±30° / ±30° 6. Specimen holders • Single tilt holder 7. Specimen tilt • Double tilt holder 8. Vacuum System Fully Dry-Vacuum system for the HRTEM (Column and Gun Section) with all required backing pumps, high vacuum pumps and Ultra-High Vacuum Pumps, suitable Pressure Gauges, Compressors and Suitable Air & Water Chillers et er quired for HRTEM operation. should be 2×10° Pa 9. Lens System System consisting of condenser lens, objective lens, diffraction, intermediate and projection lenses 10. Permissible Drifts and Aberrations 1. Specimen drift ≤ 1 m/h (Software corrected?) 11. Camera length 80mm to 80mm obteter 12. Integrated EDS Fully automated and integrated EDS system with standard sample for calibration. 13. EDS details The EDS dete			The model quoted shall be able to handle metallic (magnetic as well
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The EDS system software should allow elemental analysis and elemental mapping facility in TEMmode.			
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1	14.	Work station and	All the accessories and ports should be of International standard and
computer replaceable with components available in India.		computer	replaceable with components available in India.

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Sector Sector	EPABA-0181-209030	(a) Two larger than 24" high definition monitor(s) for HRTEM
State and		operation for split display of image recording/processing, and EDS
		analyses.
		(b) Latest compatible, branded high speed computer (i7 or higher)
		with pre-loaded licensed software for all operating parameters.
		Specify computer speed, processor, RAM (32 GB or higher), 1-2 TB
		HDD, and graphics card. All the computers for HRTEM must be
		imported /factory fitted and tested with preloaded softwares for
		operating these systems.
		(c) A separate PC (i7 or higher) with 29" HD monitor, 32GB RAM, 1-
		2 TB HDD having all loaded software should be provided. 5 copies of
		software should also be included.
		(d) Color LASER printer of reputed brand & DVD R-W drive, Optical
		mouses
		(e) Antivibration Working table required for commissioning and working of
		HRTEM must be supplied
15.	Calibration	Standard samples to check system calibration i.e., magnification and
	standards	camera length should be supplied along with the system, including
		TEM Standard Au/any other standard sample for TEM resolution,
		Mn standard for EDS energy resolution
16.	Recording System	Bottom Mounted retractable, 9 Megapixel or better CMOS camera, with 1:1
	CMOS Camera	fiber optics coupling and drift correction at live frame rates
17.	Illumination modes	High Magnification
17.	inumination modes	Low Magnification
		Low Dose/ Minimum Dose feature (MDS)
18.	Chiller and	
10.	Chiller and	Suitable compressor and chiller for the main equipment should be
	0	sumplied along with the TEM system. Class singuit systematic
	Compressor	supplied along with the TEM system. Close circuit, automatic
	-	temperature and flow rate controlled chiller
19.	Compressor User Interface	temperature and flow rate controlled chiller (a) Fully computer controlled system with window based software for
19.	-	temperature and flow rate controlled chiller(a) Fully computer controlled system with window based software for operating the Microscope along with keyboard, mouse. (b) Manual
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	User Interface	 temperature and flow rate controlled chiller (a) Fully computer controlled system with window based software for operating the Microscope along with keyboard, mouse. (b) Manual control panel using knobs, sample movement by track ball or joystick (c) Control Panel and Joystick-Control panel including multifunction keys/knobs for control and adjustment of TEM parameters (focus, magnification etc) and manual joystick control for stage in X,Y,Z tilt and rotation directions . (a) All software's used to operate the instrument, acquire and process the data should be licensed and should be factory preloaded. (b) Include software that automates adjustment of focus, astigmatism, and misalignment. (c) Include a software for stage and optics control so that one can seamlessly stitch images together. (d) Include a software that facilitate acquiring HREM assays by automatically adjusting the critical imaging parameters of a TEM microscope focus, stigmation and beam tilt. (e) Include a diffraction analysis software package to automate the selection area of electron diffraction (SAED) patterns and high resolution lattice images of crystalline samples. All software should
	User Interface Software	 temperature and flow rate controlled chiller (a) Fully computer controlled system with window based software for operating the Microscope along with keyboard, mouse. (b) Manual control panel using knobs, sample movement by track ball or joystick (c) Control Panel and Joystick-Control panel including multifunction keys/knobs for control and adjustment of TEM parameters (focus, magnification etc) and manual joystick control for stage in X,Y,Z tilt and rotation directions . (a) All software's used to operate the instrument, acquire and process the data should be licensed and should be factory preloaded. (b) Include software that automates adjustment of focus, astigmatism, and misalignment. (c) Include a software for stage and optics control so that one can seamlessly stitch images together. (d) Include a software that facilitate acquiring HREM assays by automatically adjusting the critical imaging parameters of a TEM microscope focus, stigmation and beam tilt. (e) Include a diffraction analysis software package to automate the selection area of electron diffraction (SAED) patterns and high resolution lattice images of crystalline samples. All software should preferably be from a single supplier for seamless performance. (f) Software for stimulation and magnetic property studies
20.	User Interface	 temperature and flow rate controlled chiller (a) Fully computer controlled system with window based software for operating the Microscope along with keyboard, mouse. (b) Manual control panel using knobs, sample movement by track ball or joystick (c) Control Panel and Joystick-Control panel including multifunction keys/knobs for control and adjustment of TEM parameters (focus, magnification etc) and manual joystick control for stage in X,Y,Z tilt and rotation directions . (a) All software's used to operate the instrument, acquire and process the data should be licensed and should be factory preloaded. (b) Include software that automates adjustment of focus, astigmatism, and misalignment. (c) Include a software for stage and optics control so that one can seamlessly stitch images together. (d) Include a software that facilitate acquiring HREM assays by automatically adjusting the critical imaging parameters of a TEM microscope focus, stigmation and beam tilt. (e) Include a diffraction analysis software package to automate the selection area of electron diffraction (SAED) patterns and high resolution lattice images of crystalline samples. All software should preferably be from a single supplier for seamless performance.

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è.	Stanon W.S.	EPABX-0181-2690301	& 453 website: www.nitj.ac.in email: registrar@nitj.ac.in used with the instrument or accessories to be provided by the
1	Carl sold		vendor.
			(c) The supplier should guarantee that all spares should be available
			for 10 years from the date of installation.
			(d) Vacuum Pick-up for TEM grids
			(e) Acid resistant High precision tweezer (4 no. each of straight and
			bent type)
			(f) High precision Titanium tweezers (2 no.)
			(g) TEM grids (should have one shiny and one matte finish side,
			100/200 mesh, (200 no.)
			(i) carbon coated holey grids (100 no)
	22.	Uninterrupted	On-line uninterrupted Power Supply (UPS) system should be
		Power Supply (UPS)	supplied for HRTEM and Chiller. The UPS should be able to keep the
			TEM operational in case of sudden power cut or spike and support
			the complete TEM system with all accessories with full load for
			duration of 1 hour. There should be 3 years on-site comprehensive
			warranty for UPS, including onsite replacement warranty for
			batteries from the date of installation
	23.	Pre-installation	Pre-installation requirements such as room size, tolerable limits of
		requirements	electromagnetic field and vibration (mechanical), required power
			rating, utility requirements are to be stated clearly, and to be
			verified/surveyed by the supplier at the installation site. Vendor has
			to visit site with survey tools and suggest for pre installation
			requirements at TEM site on the basis of results of site survey
			report
	24.	Recommended essential	Quote should also be submitted for recommended essential spares for uninterrupted
		spares	operation of the equipment for five years.
	25.	Maintenance	The supplier shall confirm availability of spares for a •period of 10 years from
			date of installation of TEM
	26.	Up-gradation	(i) The supplier shall supply any software for HRTEM and EDSoperation
			whenever they are upgraded.
			(ii) The equipment shall have the provision for upgradations like STEM,
			EELS etc.
	27.	Application notes	The supplier shall provide detailed application notes of HRTEM and EDSsystems in
	•		hard and soft copies.
	28.	Man Power	The supplier will have to provide a high skilled and experienced (atleast 1 year
			experience) full time operator to run the system for a period of 3-years from the date
			of installation of the system in the institute at their own cost. The amount for the 3
			years operator service might be paid on year to year basis. The operator will work as an employee of the vendor and institute shall have no responsibility for his/her
			service liabilities

(B) Installation & operational requisites:

All the prerequisites for installation operation (Special electricity, cooling water, air, any other) have to included in quote. Institute will only provide standard electricity at 220V, 50Hz, normal quality water and space.

(C) Warranty and maintenance:

1. The complete comprehensive onsite warranty for 3 years(excluding breakdown periods) for the entire system, including the filaments etc from the date of installation on the complete system, including all the subsystems.

Warranty should cover,

a) All parts including accessories and labor.

b) Free maintenance and services.

c) Regular up-gradation of software.

2. In case of breakdown during the warranty period, a competent service engineer of



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the supplier should make as many visits as are necessary to rectify the problem and replace the faulty parts, without any liability of cost. But it should be repaired within 72 working hours from the date and time of complaint lodged by the user. In case of any delay in repair without adequate justification, there will be penalty of rupees 5,000/- per day for the down time. Supplier should ensure to provide all spares required for making the instrument operational. The spares recommended for keeping in inventory along with the instrument may also be quoted.

(D) Annual maintenance contract:

After warranty, AMC (year wise) charges should also be quoted as optional.

(E) Installation Commissioning and training

Installation and commissioning should be done by the manufacturer. On-site two week training for operation and application may be given to the users free of cost. Required Insulation Gas shall be provided at site for installation.

(F) Spare parts

The supplier of the instrument must confirm in writing that the spares for the entire instrument will be available for a period of at least ten years after the model of equipment

supplied has been phased out. For frequently required spares, there should be adequate inventory with the Indian agency.

(G) Manual

One set of operating manual and service manual including detailed drawings and circuit diagrams(in English) should be provided with the instrument

(H) User list with contacts

Vendor should provide us a list of installations in India with all contact details and model details so that NIT Jalandhar can approach the contact person for any feedback. In case of any doubt about capability of the machine, the vendor will have to arrange demonstration at any site bearing the cost including the travel and other expanses of NIT Jalandhar representatives.

(I) Compliance statement

- The supplier must submit technical brochures and proper application notes adequately explaining and confirming the availability of the features in the model of the equipment being quoted.
- The supplier must submit a table indicating the compliance of the features of the model of the equipment being quoted with those given in the indent. Features not matching must be clearly indicated.
- Additional features and Features in the quoted equipment which are better than those in the indent may be clearly explained.
- The vendor must certify that the equipment and accessories quoted provide a complete package for use of HRTEM for diffraction studies, Bright Field and Dark Field Imaging, along with analysis by EDS.

(J) Other Requirements:

1. Demonstration of all the functionalities of HRTEM imaging process, showing specified resolution on standard samples such as Gold and Tin ball, and testing on various user's sample must be done at the time of installation. All standard specimens should be provided by the vendor.

2. The vendor should have at least 5HRTEM installations across the country in last 5 years. The Committee may relax the number of installation required.

3. List of spares that can be kept in stock should be provided with price

SPECIMEN PREPARATION EQUIPMENT FOR HRTEM

For Metallic Specimens (Ductile)-

S.No	Item	Description
1	Disk Punch	Preferable specifications:
		- Should be able to cut 3 mm diameter circular samples from
		ductile and soft materials
		- Should be able to cut discs from samples with thickness from 60 μm to



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2	AL AND AL		100 μm or more		
			- Should deliver discs with sharp edges		
			- Horizontal cutting action is preferred		
			All required accessories should be provided.		
			All consumables should be supplied for 5 years from installation free of cost		
	2	Disk grinder, lapping kit	Preferable specifications:		
			Disc mount with goniometer with at least 10 micron		
			graduation on the scale (automated operation is preferred)		
			- Specimen lapping kit with at least 2 heavy metal base, and at		
			least 5 ultra-flat glass lapping plates: and approximately 100		
			lapping discs for each grit size		
			- Specimen mounting hot plate and low melting polymer wax		
			rods		
			- All necessary consumables, for an uninterrupted operation		
			during warranty period, including SS and Pyrex specimen		
			mounting cylinders and mounting wax shall be supplied		
			All required accessories should be provided. All consumables		
			should be supplied for 5 years from installation free of cost.		
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3. JET POLISHER FOR TEM SAMPLE PREPARATION OF METALLIC SAMPLES

The automatic electrolyte jet thinning equipment should be able to prepare a perforated specimen of 3mm diameter for TEM from a sample thickness of about 0.5mm to a thickness of less than 50nm. The thinning unit should consist of a control unit, polishing unit. The detailed specifications of each of these units are given below:

S. No.	Item	Description
1	Control Unit for	A separate control unit should be provided incorporating power supply,
	Jet Polisher	programming and monitoring functions. It should have the following
		features:
		Should have automatic control.
		• Should have an electronic thermometer to measure temperature of
		the electrolyte.
		• Should have an adapter to connect to the polishing unit.
		• Mains voltage should be single phase, 220-240 V, 50Hz.
		• Output voltage should be in the range 0-120V DC.
		• Digital display of required parameters like current, electrolyte temperature and
		elapsed thinning time.
		• A built-in scan function to determine the correct polishing voltage for any material
		will be given preference:
		• A database or manual to accommodate up to 200 user methods of
		electrolytic thinning for different materials.
		• Automatic or manual stopping of the polishing process if the
		temperature of the electrolyte exceeds the predetermined temperature
2	Polishing	The polishing unit should be compatible to the control unit and the
	unit: for Twin	specimen should be polished from both sides simultaneously, so that the
	Jet Polsiher	structure is available with minimum deformation. The polishing unit
		should have the following features:
		• Should have a specimen holder for 3mm diameter and 0.5 mm thick
		specimens where one part of the holder should carry a platinum
		conductor so that electrical connection to the polishing circuit is
		automatically established.
		• Should have set of jets of 1mm diameter for thinning 3mm diameter
		specimens.
		• Infrared detector to stop the thinning process automatically once the
		perforation appears.



		• All the parts, which would be in contact with chemicals, should be made of corrosion-resistant material
3 Sample Holders		Twin Jet Polisher should be supplied with 1 3mm sample Holder. Please include another 3mm sample holder as optional item.
4	Power supply requirements	• 230V, 50 Hz Operation, single phase
5	a) Installation & commissioning b) Warranty	The equipment should be installed in the laboratory without additional cost. Start-up assistance and training should be included for two scientists in the laboratory. 12 months warranty from the date of acceptance of the equipment. Please quote 2 nd & 3 rd year warranty charges as optional items

4. LOW SPEED DIAMOND WHEEL SAW

S. No.	Item	Description	
1	Power Supply	• 230V, 50 Hz, Single Phase	
3	Materials	• Saw should be suitable for sectioning HARD AND BRITTLE MATERIALS like	
		Sapphire, SiC as well as other metals	
4	Variable Cutting	• 200 to 300 RPM or more	
	Speed		
5	Cutting Pressure	• 0 to 300 gms or more	
6	Wheel Diameter	System should accommodate cutting wheels @ 12.5mm Dia	
7.	Precision Cut	• Should be equipped with a micrometer screw gauge based positioning system to	
		accurately determine the thickness of the section.	
8	Diamond Wheel	System should be supplied with 1 Diamond Wheel . The vendor should also	
		include another diamond wheel under optional items.	
9	Cutting Fluid/Coolant	A pack of Coolant/Cutting Fluid should be supplied along with the equipment.	
		One additional pack should be supplied as optional item	
9	Power supply	• 230V, 50 Hz Operation, single phase	
	requirements		
10	a) Installation &	The equipment should be installed in the laboratory without additional cost. Start-up	
	commissioning	assistance and training should be included for two scientists in the laboratory.	
		12 months warranty from the date of acceptance of the equipment.	
	b) Warranty		

5. Plasma Cleaner- One unit of plasma cleaner for specimens and specimen holders. Should be compatible with both TEM and SEM samples. It should be complete system that includes a oilfree turbo-molecular pump and multistage drag pump. An appropriate gas cylinder and regulator is to be provided.



Annexure: "B"

FORMAT FOR PERFORMANCE BOND/GUARANTEE

(Undertaking from the supplier on a Non Judicial Stamp Paper of requisite duly attested by Notary) In consideration for "The Registrar, National Institute of Technology Jalandhar (hereinafter called NIT Jalandhar)having agreed to release the payment of net value as per terms and conditions of a concluded Order No.______ dated ______ (hereinafter called 'the order') for supply of _______ (here in after called 'the Equipment //tem)to us Messrs _______ (hereinafter called 'the supplier') on submission of a Performance Bond to the satisfaction of NIT Jalandhar for the due performance of the said order.

We, Messer's ______ hereby submit the FDR/TDR No. ______ issued by ______ (Name of Bank) for ______ pledged in favour of Registrar, NIT Jalandhar as performance guarantee amount and hereby irrevocably, unconditionally and absolutely undertake against any loss or damage caused or suffered by NIT Jalandhar by reason of any failure of the supplier to perform or omission or negligence to perform any part of its obligations to the satisfaction of NIT Jalandhar in terms of the order.

We, the supplier, do hereby authorize Registrar, NIT Jalandhar to forfeit this Performance Guarantee amount / undertake to pay the amount due and payable under this guarantee without any demur merely on a demand from the NIT Jalandhar stating that the amount claimed is due by way of loss or damage caused to or would be caused to or suffered by the NIT Jalandhar by reason of any breach by us of any of the terms and conditions contained in the said order or by reason of our failure or omission or negligence to perform the said order or any part thereof. We, the Supplier, undertake to pay to NIT Jalandhar any amount so demanded by NIT Jalandhar, notwithstanding:

a) Any dispute or difference between NIT Jalandhar and supplier or any other person or between the supplier or any person or any suit or proceeding pending before any court or tribunal or arbitrator relating thereto; or

b) The invalidity, irregularity or unenforceability of the order; or

c) Any other circumstances which might otherwise constitute discharge of this guarantee, including any act of omission or commission on the part of NIT Jalandhar to enforce the obligations by the supplier or any other person for any reason whatsoever.

We, the Supplier, further agree that the performance Bond/ Guarantee herein contained shall be continued one and remain in full force and effect during the period that would be taken for the performance of the said order and that it shall continue to be enforceable till all the dues of the NIT Jalandhar under or by virtue of the said order have been fully paid and its claims satisfied or discharged or till the office of the Registrar, NIT Jalandhar certifies that terms and conditions of the said order have been fully and promptly carried out by us and accordingly discharges this Performance Bond/ Guarantee.

We, the Supplier, further agree with NIT Jalandhar, that NIT Jalandhar shall have the fullest liberty without our consent and without affecting in any manner our obligations hereunder to vary any of the terms and conditions of the said order or to extend time of performance by the said supplier from time to time or to postpone for any time or from time to time and of the powers exercisable by the NIT Jalandhar against the said supplier and forbear or enforce any of the terms and conditions relating to the order and we shall not be relieved from our liability by reason of any such variation or extension being granted to us or for any forbearance, act or omission on the part of NIT Jalandhar or any indulgence by NIT Jalandhar to us or by any such matter or thing whatsoever which under the law relating to sureties would, but for this provision, have effect of so relieving us.

This Performance Bond/Guarantee will not be discharged due to the change in the constitution of the supplier. We, the Supplier, undertake not to revoke this Performance Bond / Guarantee except with the prior consent of NIT Jalandhar in writing.

The disputes relating to this Bank Performance Bond / Guarantee shall be resolved as per the terms and conditions of the order.



Annexure "C"

FORMAT FOR PERFORMANCE BOND (BANK GUARANTEE)

In consideration for the Registrar, National Institute of Technology Jalandhar, *(hereinafter called NIT Jalandhar)* having agreed to release the payment of net value as per terms and conditions of a concluded Order No. ______ dated ______ *(hereinafter called 'the order')* for supply of ______

(hereinafter called 'the Equipment /Item) to Messrs_____(hereinafter called 'the supplier') on submission of a Bank Guarantee to the satisfaction of NIT Jalandhar for the due performance of the said order.

We, ______ (hereinafter called 'the Bank') at the request of the supplier do, as a primary obliger and not merely as surety, hereby irrevocably, unconditionally and absolutely undertake against any loss or damage caused or suffered by NIT Jalandhar by reason of any failure of the supplier to perform or omission or negligence to perform any part of its obligations to the satisfaction of NIT Jalandhar in terms of the order.

We, the Bank do hereby undertake to pay the amount due and payable under this guarantee without any demur merely on a demand from NIT Jalandhar stating that the amount claimed is due by way of loss or damage caused to or would be caused to or suffered by NIT Jalandhar by reason of any breach by the said supplier of any of the terms and conditions contained in a said order or any part thereof. Any such demand made on the Bank shall be conclusive as regards the amount due and payable by the bank under this guarantee, which shall not be considered as satisfied by any intermediate payment or satisfaction of any part of or obligation hereunder. However, our liability under this guarantee shall be restricted to an amount not exceeding _____.

We, the Bank, undertake to pay to NIT Jalandhar any amount so demanded by NIT Jalandhar, notwithstanding a). Any dispute and difference between NIT Jalandhar and supplier or any other person or between the supplier or any person or any suit or proceeding pending before any court or tribunal or arbitrator relating thereto or

a). The invalidity, irregularity or unenforceability of the order or

b). Any other circumstances which might otherwise constitute discharge of this guarantee, including any act of omission or commission on the part of NIT Jalandhar to enforce the obligations by the supplier or any other person for any reason whatsoever.

We, the Bank, further agree that the guarantee herein contained shall continue and remain in full force and effect during the period that would be taken for the performance of the said order and that it shall continue to be enforceable till all the dues of NIT Jalandhar under or by virtue of the said order have been fully paid and its claims satisfied or discharged or till the office of the Registrar, NIT Jalandhar confirms that the terms and conditions of the said order have been fully and promptly carried out by the said supplier and accordingly discharge this guarantee.

We, the Bank, hereby agree and undertake that any claim which the bank may have against the supplier shall be subject to and subordinate to the prior payment and performance in full of all the obligations of the bank hereunder and the bank will not, without prior written consent of NIT Jalandhar, exercise any legal rights or remedies of any kind in respect of any such payment or performance so long as the obligations of the bank hereunder remain owning and outstanding, regardless of the insolvency, liquidation or bankruptcy of the supplier or otherwise. We, the Bank, will not counter claim or set off against its liabilities to NIT Jalandhar hereunder any sum outstanding to the credit of NIT Jalandhar with it.

We, the Bank, further agree with NIT Jalandhar , that NIT Jalandhar shall have the fullest liberty without our consent and without affecting in any manner our obligations hereunder to vary any of the terms and conditions of the said order or to extend time of performance by the said supplier from time to time or to postpone for any time or from time to time and of the powers exercisable by the NIT Jalandhar against the said supplier and forbear or enforce any of the terms and conditions relating to the order and we shall not be relieved from our liability by reason of any such variation or extension being granted to the said supplier or for any forbearance, act or omission on the part of NIT Jalandhar or any indulgence by NIT Jalandhar to the said supplier or by any such matter or thing whatsoever which under the law relating to sureties would, but for this provision, have effect of so relieving us.

This guarantee will not be discharged due to the change in constitution of the Bank or the supplier.

We, the Bank, lastly undertake not to revoke this Guarantee during its currency except with the prior consent of NIT Jalandhar in writing.

The disputes relating to this Bank Guarantee shall be resolved as per the terms and conditions of the order.



Annexure "D"

FORMAT FOR MANUFACTURER'S AUTHORIZATION FORM

To, The Registrar Dr B. R Ambedkar National Institute of Technology Jalandhar

Sub. : e-Tender for "_____".

Dear Sir,

 We,_______, who are established and reputed manufacturers of

 _______, having factory/office at _______, hereby authorize M/s

 _______ [name & address of agents/distributors] to bid, negotiate and conclude the order

 with you for the above goods manufactured by us.

this business against this specific tender as for all business in the entire territory of India.

We hereby extend our full guarantee and warranty as per the terms and conditions of tender for the goods offered for supply against this invitation for bid by the above supplier.

*specify in detail manufacturer's responsibilities the services to be rendered by

M/s_____ are as under: i) ______ ii)

[Specify the services to be rendered by the agent/distributor] In case duties of the agent/distributor are changed or agent/ distributor is changed it shall be obligatory on us to automatically transfer all the duties and obligations to the new Indian Agent failing which we will ipso-facto become liable for all acts of commission or omission on the part of new Indian Agent/ distributor.

Yours faithfully,

[Name & Signature] For and on behalf of M/s. _____ [Name of manufacturer]



Annexure "E"

DECLARATION REGARDING BLACKLISTING / DEBARRING FOR TAKING PART IN TENDER Self Attested

I / We	_ (Tenderer) hereby	(Tenderer) hereby declare that the firm / agency namely				
M/s		has not been blacklisted	or			
debarred in the past by Union /	State Government	or organization from taking part	in			
Government tenders in India.						

Or

I / We	(Tende	rer) hereby decla	re that the	=irm /	agency nam	ely
M/s				was	blacklisted	or
debarred by Union / Stat	e Government or a	any Organization	from taking	g part	in Governm	ent
tenders for a period of						

years w.e.f.	to	The period is over on
and now the firm/c	company is entitled to take part i	in Government tenders.

In case the above information found false I / we are fully aware that the tender/ contract will be rejected / cancelled by Director, NIT Jalandhar, and EMD / SD shall be forfeited.

DEPONENT	
Attested:	
(Stamp of Company with author	rized sign)
Name	
Address	



Annexure: "F"

CERTIFICATE OF WARRANTY

- i) .I/We certify that the warranty shall be for a period of ______ years for ______ and starting from the date of satisfactory installation, commissioning and handing over of the Equipment /Item and of the works conducted therewith covered under the supply order in working order. During the warranty period, I/we shall provide free "after sale service" and the replacement of any part(s) of the Equipment /Item or rectification of defects of work of the Equipment /Item will be free of cost. The replacement of the parts shall be arranged by us, at our own cost and responsibility. We undertake that the above warranty shall begin only from the date of satisfactory and faultless functioning of the Equipment /Item for 60 days at NIT Jalandhar premises. The benefit of change in dates of the warranty period shall be in the interest of the use/your organization.
- ii). During the warranty period, we shall provide at least_____ preventive maintenance visits.
- iii).Uptime Guarantee: During the warranty period, we will be responsible to maintain the Equipment /Item in good working conditions for a period 350 days (i.e. 95% uptime) in a block of 365 days.
 - a). All complaints will be attended by us within 2 working days of receipt of the complaint in our office.
 - b). In case there is delay of more than 2 days in attending to a complaint from our side then you can count the number of days in excess of the permissible response time in the downtime. The above said response time of 2 days for attending to a complaint by us will not be counted in the downtime.
 - c). **Penalty**: We shall pay a penalty equivalent to **0.5 % of the FOB/CIF** value of the Equipment /Item for every week or part thereof delay in rectifying the defect.

Note: The right to accept the reason (s) for delay and consider reduction or wave off the penalty for the same shall be at the sole discretion of Director, NIT Jalandhar

iv). We certify that the Equipment /Item being/ quoted is the latest model and that spares for the Equipment /Item will be available for a period of at least ______ years and we also guarantee that we will keep the organization informed of any update of the Equipment /Item over a period of ____ years.

- v). We guarantee that in case we fail to carry out the maintenance within the stipulated period, NIT Jalandhar reserves the right to get the maintenance work carried out at our risk, cost and responsibility after informing us. All the expenses including excess payment for repairs/maintenance shall be adjusted against the Performance Bank Guarantee. In case the expenses exceed the amount of Performance Bank Guarantee, the same shall be recoverable from us with/without interest in accordance with the circumstances.
- vi).We shall try to repair the Equipment /Item at NIT Jalandhar premises itself. However, the Equipment /Item will be taken to our site on our own expenses in case it is not possible to repair the same at NIT Jalandhar. We shall take the entire responsibility for the safe custody and transportation of the Equipment /Item taken out for repairs till the Equipment /Item is rehabilitated to the NIT Jalandhar after repair Any loss of Equipment /Item or its accessories under its charge on account of theft, fire or any other reasons shall be at our sole risk and responsibility which will be compensated to NIT Jalandhar for such losses at the FOB/CIF value for the damaged/lost Equipment /Item part, including accessories.
- vii. We undertake to perform calibration after every major repair/breakdown/taking the Equipment /Item for repair out of NIT Jalandhar premises.
- viii. In case of extended warrantee, we undertake to carry out annual calibration of the Equipment /Item.
- ix. We guarantee that we will supply spare parts if and when required on agreed basis for an agreed price. The agreed basis could be an agreed discount on the published catalogue price.
- x. We guarantee to the effect that before going out of production of spare parts, we will give adequate advance notice to you so that you may undertake to procure the balance of the life time requirements of spare parts.
- xi. We guarantee the entire unit against defects of manufacture, workmanship and poor quality of components.



Annexure-G

SELF DECLARATION [For Local Content of Products, Services or Works]

To,

The Director Dr.B.R.Ambedkar NIT Jalandhar

- 1. With reference to Order No. P- 45021/2/2017-PP(BE-II) dated 16-09-2020 of DPIIT, Ministry of Commerce and Industry, Govt. of India, we fall under the following category of supplier (please tick the correct category) for the items for which this tender has been floated and being bided.
 - □ Class I local supplier has local content equal to more than 50%. Local contents added at (name of location).
 - Class II local supplier has local content more than 20% but less than 50%. Local contents added at _____(name of location).
 - Non-local supplier has local content less than or equal to 20%. Local contents added at ______ (name of location).
- 2. We are solely responsible for the abovementioned declaration in respect of category of supplier. False declarations will be in breach of the Code of Integrity under Rule 175(1)(i)(h) of the General Financial Rules for which we may can be debarred for up to 2 years as per Rule 151(iii) of the General Financial Rules along with such other actions as may be permissible under law.

Signature & seal of the company

Name and address of the organization

Note: In cases of procurement for a value in excess of Rs. 10 crores, the 'Class-I local supplier' / 'Class-II local supplier' shall be required to provide a certificate from the statutory auditor or cost auditor of the company (in the case of companies) or from a practicing cost accountant or practicing chartered accountant (in respect of suppliers other than companies) giving the percentage of local content.